

In the United States Patent and Trademark Office

Serial Number: _____

Appn. Filed: _____

Applicant(s): Ming Lai et al

Appn. Title: Method of Programmed Displacement...

Examiner/GAU: _____

Disclosure Document Reference Letter

Date: 11/13/03

Assistant Commissioner for Patents
Washington, District of Columbia 20231

Sir:

A disclosure document as identified below was previously filed in the Patent and Trademark Office. As this disclosure relates to the above patent application, applicant(s) request that this Disclosure Document be retained and referenced to the above application.

Disclosure Document Title: Method of Programmed Displacement...

Disclosure Document Number: 519396

Disclosure Document Filing Date: Oct. 7, 2002

Very Respectfully,

Lai

Signed Name

Signed Name

Printed Name, First Applicant

Printed Name, Joint Applicant

P.O. Box 10845

Address of First Applicant

Address of Joint Applicant

Pleasanton, CA 94588

Programmed Displacement

PTO/SB/08A (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449/PTO		<i>Use a separate sheet if more space is required.</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT			
<i>(Use as many sheets as necessary)</i>			
Sheet	1	of	1
		Complete if Known	
		Application Number	
		Filing Date	
		First Named Inventor	Lai, Ming
		Art Unit	
		Examiner Name	
		Attorney Docket Number	

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear
		Country Code ³ *Number ⁴ *Kind Code ⁵ (if known)			
		WO 99/55216 WIPO	11/04/1999		
		WO 00/04952 WIPO	02/03/2000		

Examiner Signature		Date Considered	
-----------------------	--	--------------------	--

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹Applicant's unique citation designation number (optional). ²See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.

U. S. PATENT DOCUMENTS

5144630 9/1/1992 Lin

Multiwavelength solid state laser using frequency conversion techniques

5401948 3/1995 Krichever et al

5825562 10/20/1998 Lai et al.

Method of continuous motion for prolong usage of optical elements under the irradiation of intensive laser beams

6031854 2/29/2000 Lai

Diode-pumped cascade laser for deep UV generation